3/26/04

INFORMATION DISCLOSURE CITATION PTO-1449	ATTY. DOCKET NO. P132-US	SERIAL NO. 10/811,449 Not Yet Assigned
	APPLICANT Jim Dunphy, et al.	
	FILING DATE Herewith	GROUP Not Yet Assigned

U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
DLi	U.S Pub App No. 2003/0002019	1/2/03	Miller			
	U.S Pub App No. 2002/0056898	5/16/02	Lopes, et al.			
	U.S Pub App No. 2002/0063322	5/30/02	Robbins, et al.			
	6,300,294	10/9/01	Robbins, et al.			
	5,694,740	12/9/97	Martin, et al.			
	5,936,758	8/10/99	Fisher, et al.			
	5,610,438	3/11/97	Wallace, et al.			
DLi	5,512,374	4/30/96	Wallace, et al.			

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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

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	Micromotor Operation in a Liquid Environment" Dhuler, IEEE 1992 pgs 10-13
	"Optimization of Lubricants fir silica Micromotors" Zarrd, Sensors and Actuators A 46-47 (1995) 598-600
	"Fabrication of packaged thin beam structures by an improved driving method"Masato Ohtsu, IEEE (1996) 0-7803-2985-6, pgs 228-233
	"Operation of electrostatic micromotors in liquid environments" Mehran Mehregany, J. Micromech. Microeng. 2 (1992) 1-3
	"Nanotribology and nanomechanics of MEMS devices", Nharad Bhushan, IEEE0-7803-298-5-6, pgs 91-98
	"Micromotor dynamics in lubricating fluids"Keren Deng, J. Micromech. Microeng. 4 (1994) 266-269
	"Stiction reduction processes for surface mciromachines" Roya Maboudian Tribology letters 3 (1997) 215-221
	"Friction and Pull-off Force on Silicon Surface Modified by FIB" Ando IEEE 1996, 0-7803-2985-6/96, pgs 349-353
	"Measurement of Micromoto Dynamics in Lubricating Fluids" Deng IEEE
DLi	"Friction and Wear studies on Lubricants and materials Applicable to MEMS" Shigehisa Suzuki, IEEE 1991, pgs 143-147

EXAMINER DLi DATE CONSIDERED 6/2/05

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DL	5,939,785	8/17/99	Klonis, et al.			
	5,411,769	8/17/99	Hombeck			
	6,204,085	3/20/01	Strumpell, et al.			
	2003/0064149	4/3/03	Miller			
	6,259,551	7/10/01	Jacobs			
	5,447,600	9/5/95	Webb			
	~~6,300,294~~	~~10/9/01~~	~~Robbins, et al.~~			duplicated
	6,086,726	7/11/00	Renk, et al.			
	6,475,570	11/5/02	Jacobs			
	2004/0100677	5/27/04	Huibers, et al.			
DL	2004/0125346	7/1/04	Huibers			

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DL	W. Robert Ashurst, et al., WAFER LEVEL ANTI-STICTION COATINGS FOR MEMS., Sensors and Actuators A 104 (2003), Pgs 213-221.
DL	W. Robert Ashurst et al., VAPOR PHASE ANTI-STICTION COATINGS FOR MEMS, Pgs 1-6.
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	B.C. Bunker, et al., THE IMPACT OF SOLUTION AGGLOMERATION ON THE DEPOSITION OF SELF-ASSEMBLED MONOLAYERS, 2000 American Chemical Society, Pgs 7742-7751.
	W. Robert Ashurst, et al., ALKENE BASED MONOLAYER FILMS AS ANTI-STICTION COATINGS FOR POLYSILICON MEMS, Berkeley Sensor & Actuator Center, 4 pgs.
	S Imad-Uddin Ahmed, et al., USING SELF ASSEMBLED MONOLAYERS TO REDUCE FRICTION AND WEAR IN POLYSILICON BASED MEMS, 2000, Pgs. 1-18.
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DLe	2004/0012838	1/22/04	Huibers			
	2004/0100594	5/27/04	Huibers, et al.			
	2004/0156090	8/12/04	Patel, et al.			
	5,835,256	11/10/98	Huibers			
	6,046,840	4/4/00	Huibers			
	6,844,959	1/18/05	Huibers, et al.			
	6,867,897	3/15/05	Patel, et al.			
DLe	5,287,096	2/15/94	Thompson, et al.			

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